

## HL 86: Oxide Semiconductors for Device and Energy Applications 2

Time: Thursday 15:00–16:45

Location: H11

HL 86.1 Thu 15:00 H11

**How Seebeck coefficient measurements help determine oxide transport properties** — ●ALEXANDRA PAPADOGIANNI<sup>1</sup>, OLIVER BIERWAGEN<sup>1</sup>, MARK E. WHITE<sup>2</sup>, JAMES S. SPECK<sup>2</sup>, ZBIGNIEW GALAZKA<sup>3</sup>, KELVIN H. L. ZHANG<sup>4</sup>, YINGGE DU<sup>4</sup>, and SCOTT A. CHAMBERS<sup>4</sup> — <sup>1</sup>Paul-Drude-Institut für Festkörperelektronik, Hausvogteiplatz 5-7, D-10117 Berlin, Germany — <sup>2</sup>Materials Department, University of California, Santa Barbara, California 93106, USA — <sup>3</sup>Leibniz-Institut für Kristallzüchtung, Max-Born-Straße 2, D-12489 Berlin, Germany — <sup>4</sup>Pacific Northwest National Laboratory, Richland, Washington 99352, USA

Measuring the Hall effect is a common and convenient method to investigate the electrical transport properties of thin samples, providing us with an estimate of integral sheet carrier concentration. In low-mobility p-type semiconducting oxides, such as the Sr-doped LaCrO<sub>3</sub>, however, Hall measurements fail. For such instances, studying thermoelectric properties, namely the Seebeck coefficient, can be a simple alternative, which provides us with the carrier type and volume carrier concentration. A combination of Seebeck and Hall measurements can moreover be used for estimating the actual thickness of a carrier system within a semiconductor. As an example, an application on n-type SnO<sub>2</sub> shows how this method can help distinguish bulk carriers, with homogeneous depth distribution, from sheet carriers accumulated within a thin layer.

HL 86.2 Thu 15:15 H11

**Metal incorporation and reaction-kinetics for the molecular beam epitaxial growth of (Ga<sub>x</sub>In<sub>1-x</sub>)<sub>2</sub>O<sub>3</sub>** — ●PATRICK VOGT and OLIVER BIERWAGEN — Paul-Drude-Institut für Festkörperelektronik, Hausvogteiplatz 5–7, 10117 Berlin, Germany

This contribution presents the metal incorporation and reaction-kinetics study of the plasma-assisted molecular beam epitaxial (MBE) growth of the transparent semiconducting oxide alloy (Ga<sub>x</sub>In<sub>1-x</sub>)<sub>2</sub>O<sub>3</sub>. By using MBE, an impinging Ga- (Φ<sub>Ga</sub>), In- (Φ<sub>In</sub>), and oxygen-flux (Φ<sub>O</sub>) react amongst others to (Ga<sub>x</sub>In<sub>1-x</sub>)<sub>2</sub>O<sub>3</sub> on a heated, single-crystalline substrate under ultra-high vacuum conditions. The data obtained were measured *in-situ* by a laser reflectometry (LR) set-up and a line-of-sight quadrupole mass spectrometer (QMS) or *ex-situ* by energy dispersive X-ray spectroscopy (EDX). The LR allowed measuring the growth-rate (ρ), the QMS enabled identifying the species that desorbed off the substrate which are not incorporated into the alloy, and the EDX measurements revealed the In incorporation *x* and the reciprocal Ga incorporation 1-*x*.

We present the growth rate dependencies of the binary grown In<sub>2</sub>O<sub>3</sub> and Ga<sub>2</sub>O<sub>3</sub> as function of growth temperature (*T<sub>G</sub>*). Furthermore, we show the dependence of ρ and *x* for the ternary grown alloy on *T<sub>G</sub>*, the metal-to-oxide ratio (*r<sub>MeO</sub>* = (Φ<sub>In</sub> + Φ<sub>Ga</sub>)/Φ<sub>O</sub>), and the In-to-Ga ratio (*r<sub>InGa</sub>* = Φ<sub>In</sub>/Φ<sub>Ga</sub>).

The measured discrepancy of ρ for the binary grown oxides compared to *x* for the ternary grown alloy can be explained by the different adhesion energies for In and Ga on the (Ga<sub>x</sub>In<sub>1-x</sub>)<sub>2</sub>O<sub>3</sub> surfaces.

HL 86.3 Thu 15:30 H11

**Application of Cr<sub>2</sub>O<sub>3</sub> and Cr<sub>2</sub>O<sub>3</sub>:Mg as a Buffer Layer in Organic Solar Cells** — ●DARAGH MULLARKEY<sup>1</sup>, ELISABETTA ARCA<sup>1</sup>, LINDA CATTIN<sup>2</sup>, JEAN CHRISTIAN BERNÉDE<sup>3</sup>, and IGOR SHVETS<sup>1</sup> — <sup>1</sup>School of Physics and CRANN, Trinity College Dublin, University of Dublin, Ireland — <sup>2</sup>Université de Nantes, Institut des Matériaux Jean Rouxel, France — <sup>3</sup>Université de Nantes, MOLTECH-Anjou, France

The use of undoped Cr<sub>2</sub>O<sub>3</sub> and p-type Cr<sub>2</sub>O<sub>3</sub>:Mg as an anode buffer layer in organic solar cells is explored. The effects of buffer layer thickness, roughness, and growth conditions on the properties of the solar cell were studied. These effects were investigated for solar cells grown on both indium tin oxide and fluorine doped tin oxide. In both cases, Cr<sub>2</sub>O<sub>3</sub> and Cr<sub>2</sub>O<sub>3</sub>:Mg were found to improve the efficiency of the solar cell.

The band offsets between the anode material and the buffer layer, as well as between the buffer layer and the organic absorber were studied by X-ray Photoelectron Spectroscopy (XPS) and Ultra Violet Photoelectron Spectroscopy (UPS). The efficiency of the solar cells is discussed in terms of the experimentally determined band alignment.

HL 86.4 Thu 15:45 H11

**TiO<sub>2</sub> laminated Silicon microstructures based stable photocathode for water splitting** — ●CHITTARANJAN DAS<sup>1</sup>, MASSIMO TALLARIDA<sup>2</sup>, and DIETER SCHMEISSER<sup>3</sup> — <sup>1</sup>Angewandte Physik / Sensorik, BTU Cottbus-Senftenberg, Germany — <sup>2</sup>ALBA-Barcelona — <sup>3</sup>Angewandte Physik / Sensorik, BTU Cottbus-Senftenberg, Germany

The photoelectrochemical (PEC) water splitting is one of the most efficient ways to obtain hydrogen from water using solar power which can be used as carbon free fuel. The PEC device can be redesigned using semiconducting material that will convert solar radiation to H<sub>2</sub>. Silicon can be one of the best choices for PEC due to its success in solar cells technology. There are certain issues with Si such as stability in electrochemical medium [1] and higher surface reflectance (25%) which limits the Si as an ideal candidate for PEC technique [2].

In the present work we addressed these issues by surface structuring and laminating the surface with metal oxide. The microstructuring of Si was done by electrochemical method. The Si microstructure photocathode was stabilized by thin layer of ALD grown TiO<sub>2</sub> film. The microstructuring and lamination of Si photocathode by ALD layer of TiO<sub>2</sub> decreased the reflectance of the surface and shift the onset potential towards anodic direction by 350 mV with a prolonged stability over 60 hours [3].

[1] C. Levy-Clement, J. Electrochem. Soc 1991, 12, 69 [2] J. Oh, et al. Energy Environ. Sci., 2011, 4, 1690 [3] C. Das, et al. Nanoscale 2015, 7, 7726

HL 86.5 Thu 16:00 H11

**Optical and Magneto-Optical Investigation of Normal and Disordered ZnFe<sub>2</sub>O<sub>4</sub> in Relation to Magnetic Properties** — ●VITALY ZVIAGIN<sup>1</sup>, PETER RICHTER<sup>2</sup>, YOGESH KUMAR<sup>1</sup>, ISRAEL LORITE<sup>1</sup>, MICHAEL LORENZ<sup>1</sup>, DIETRICH R.T. ZAHN<sup>2</sup>, GEORGETA SALVAN<sup>2</sup>, PABLO ESQUINAZI<sup>1</sup>, MARIUS GRUNDMANN<sup>1</sup>, and RÜDIGER SCHMIDT-GRUND<sup>1</sup> — <sup>1</sup>Universität Leipzig, Institut für Experimentelle Physik II, Linnéstr. 5, Germany — <sup>2</sup>Technische Universität Chemnitz, Semiconductor Physics, Reichenheiner Str. 70, Germany

We present the magneto-optical dielectric tensor of normal and disordered ZnFe<sub>2</sub>O<sub>4</sub> grown at different temperatures on MgO (100) and SrTiO<sub>3</sub> (100) substrates by pulsed laser deposition. Optical transitions in the diagonal element of the dielectric function, obtained by spectroscopic ellipsometry, are identified as transitions from O<sub>2p</sub> to Fe<sup>3+</sup> 3d and 4s bands. Via the off-diagonal element, obtained by magneto-optical Kerr effect spectroscopy, the observed features are confirmed to be similar to the mentioned transitions. One transition in particular, namely a transition from O<sub>2p</sub> to tetrahedrally coordinated Fe<sup>3+</sup> cation, located at ~ 3.5 eV, suggests disorder of the normal crystal structure. Its amplitude is highest for the sample grown at the lowest temperature in both the diagonal and off-diagonal elements of the dielectric tensor. Furthermore, the overall magnetic response, measured by SQUID, is highest for the sample grown at the lowest temperature, suggesting that the presence of Fe<sup>3+</sup> on the tetrahedral sites is directly related to the ferrimagnetic order of the crystal due to the dominating nature of the oxygen mediated coupling between the two lattice sites.

HL 86.6 Thu 16:15 H11

**Monitoring Proton Diffusion in Thin Films of Tungsten Oxide** — ●SIMON BURKHARDT<sup>1</sup>, SABRINA DARMAWI<sup>1</sup>, MATTHIAS T. ELM<sup>1,2</sup>, and PETER J. KLAR<sup>1</sup> — <sup>1</sup>I. Physikalisches Institut, Justus-Liebig-Universität Gießen, Heinrich-Buff-Ring 16, 35392 Gießen — <sup>2</sup>Physikalisch-Chemisches Institut, Justus-Liebig-Universität Gießen, Heinrich-Buff-Ring 17, 35392 Gießen

The reversible change of the optical properties of materials due to the electrochemical insertion of ions is called electrochromism. Tungsten-VI oxide (WO<sub>3</sub>) and its electrochromic properties have been intensively studied since 1969 as a model system which nowadays can be found in applications like smart window systems or other coated glasses. However fundamental questions concerning the colouration mechanism are still under discussion. A combination of electrochemical proton insertion and *in situ* UV/Vis-transmission spectroscopy is applied to provide new insights. With the developed set up it is not only possible to investigate the time-dependence of the colouration behaviour, but it also allows a spatially resolved analysis of the colouration process and

thus the ion diffusion in electrochromic thin films. To investigate the diffusion of protons, thin films of  $\text{WO}_3$  are deposited on TCO-coated substrates via electron beam evaporation and coated with a structured PMMA layer to enable local ion insertion. Significant differences in the colouration behaviour of amorphous and crystalline  $\text{WO}_3$  films can be observed which will be compared with a simulation of lateral 1D diffusion processes.

HL 86.7 Thu 16:30 H11

**Oxygen Vacancies in the Ultrathin  $\text{SiO}_2$  Interfacial Layer of High-K/Metal Gate CMOS Devices** — •FLORIAN LAZAREVIC<sup>1,2</sup>, ROMAN LEITSMANN<sup>1,2</sup>, PHILIPP PLÄNITZ<sup>1</sup>, and MICHAEL SCHREIBER<sup>2</sup>  
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We study oxygen vacancy defect levels in ultrathin  $\text{SiO}_2$  layers in metal-oxide-semiconductor devices. First principles calculations were performed to model a  $\text{Si}/\text{SiO}_2/\text{HfO}_2$  gate stack and a  $\text{SiO}_2$  bulk reference system. The extremely thin  $\text{SiO}_2$  layer thickness and dissimilar structural and electronic properties of the adjacent layers (namely  $\text{Si}$  and  $\text{HfO}_2$ ) result in a degeneration and stabilization of certain  $\text{SiO}_2$  bulk defects. We find that partial H passivation of the vacancies additionally stabilizes defects energetically which are related to the leakage current in CMOS devices. Furthermore the incorporation of F atoms has a large influence on the stability of H passivated  $\text{SiO}_2$  defects.